

<b>Notic of References Cited</b>	Application/Control No.	Applicant(s)/Patent Under Reexamination	
	10/075,602	HUNG ET AL.	
	Examiner	Art Unit	Page 1 of 1
	Lynette T. Umez-Eronini	1765	

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	C	US-4713141	12-1987	Tsang	438/714
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	I	US-5269879	12-1993	Rhoades et al.	156/643
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**NON-PATENT DOCUMENTS**

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	U	Abraham et al., Methods and Apparatus for Etching Semiconductor Wafers, August 21. 1997, PCT WO 97/30472, pp. 1-23.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.